



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Rajesh Tiwari, et al. Docket No: TI-36211
Serial No: 10/663,948 Conf. No: 3857
Examiner: Phat X. Cao Art Unit: 2814
Filed: 09/16/2003
For: DUAL DEPTH TRENCH TERMINATION METHOD FOR IMPROVING CU-BASED
INTERCONNECT INTEGRITY

ELECTION

Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

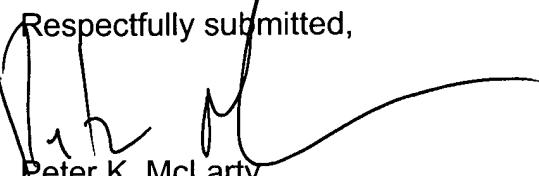
MAILING CERTIFICATE UNDER 37 C.F.R. § 1.8(a)
I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 11-24-04.

Ann Trent
Ann Trent

Dear Sir:

This election is offered in response to the Examiner's restriction requirement mailed October 12, 2004.

Applicants hereby elect to pursue Group I of Claims 1-4 and 9, drawn to a process of making a semiconductor device, without traversing the Examiner's restriction requirement.

Respectfully submitted,

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